

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant(s): LEE, Joo-Hyong; SON, Jeong-Hwan

Application No.:

Group:

Filed: January 21, 2000

Examiner:

For: METHOD OF FABRICATING TWIN WELL CMOS DEVICE

11000 U.S. PTO
09/983066



#3 | PRIORITY
PAPER
1-4-02
R. Stokes

LETTER

Assistant Commissioner for Patents
Box Patent Application
Washington, D.C. 20231

January 21, 2000
1607-0189P

Sir:

Under the provisions of 35 USC 119 and 37 CFR 1.55(a), the applicant hereby claims the right of priority based on the following application(s):

<u>Country</u>	<u>Application No.</u>	<u>Filed</u>
REPUBLIC OF KOREA	99-1909	01/22/99

A certified copy of the above-noted application(s) is(are) attached hereto.

If necessary, the Commissioner is hereby authorized in this, concurrent, and future replies, to charge payment or credit any overpayment to deposit Account No. 02-2448 for any additional fees required under 37 C.F.R. 1.16 or under 37 C.F.R. 1.17; particularly, extension of time fees.

Respectfully submitted,

BIRCH, STEWART, KOLASCH & BIRCH, LLP

By: 

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Attachment
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103-205-8000
LEE, J. et al
1607-189P
1061

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10/23/01

대한민국 특허청

KOREAN INDUSTRIAL PROPERTY OFFICE

별첨 사본은 아래 출원의 원본과 동일함을 증명함.

This is to certify that the following application annexed hereto
is a true copy from the records of the Korean Industrial
Property Office.

출원번호 : 1999 특허출원 제1909호
Application Number

출원년월일 : 1999년 1월 22일
Date of Application

출원인 : 엘지반도체주식회사
Applicant(s)



1999년 2월 22일

특허청

COMMISSIONER

